

DOCKET NO.: 263787US26PCT/ssa

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi MASHIMA, et al.

SERIAL NUMBER: 10/518,371

GROUP: 1715

FILED: December 28, 2004

EXAMINER: Kelly M. Gambetta

FOR: METHOD FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION AND APPARATUS FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION

REQUEST TO CORRECT TITLE OF INVENTION

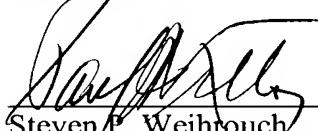
MAIL STOP ISSUE FEE
COMMISSIONER FOR PATENTS
P.O. BOX 1450
ALEXANDRIA, VA 22313-1450

SIR:

In the matter of the above-identified application for patent, we hereby request correction of your records to reflect the correct title of the invention. The title of the invention should read as follows: **METHOD FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION AND APPARATUS FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION.**

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, L.L.P.



Steven P. Weihrouch
Registration No. 32,829

Customer Number

22850

Tel. (703) 413-3000
Fax. (703) 413-2220
(OSMMN 07/09)

Paul Killos
Registration No. 58,014